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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/500,214 Confirmation No. : 2535
First Named Inventor : Takuya SUGAWARA
Filed : June 28, 2004
TC/A.U. : 2823
Examiner : M. Estrada

Docket No. : 010986.55104US
Customer No. : 23911

Title : Substrate Treating Method and Production Method for
Semiconductor Device

REPLY

Mail Stop AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following amendments and remarks are respectfully submitted in response to the non-final Office Action dated July 25, 2006.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 7 of this paper.